MRS BULLETIN

June 1988

Volume XIII, Number 6

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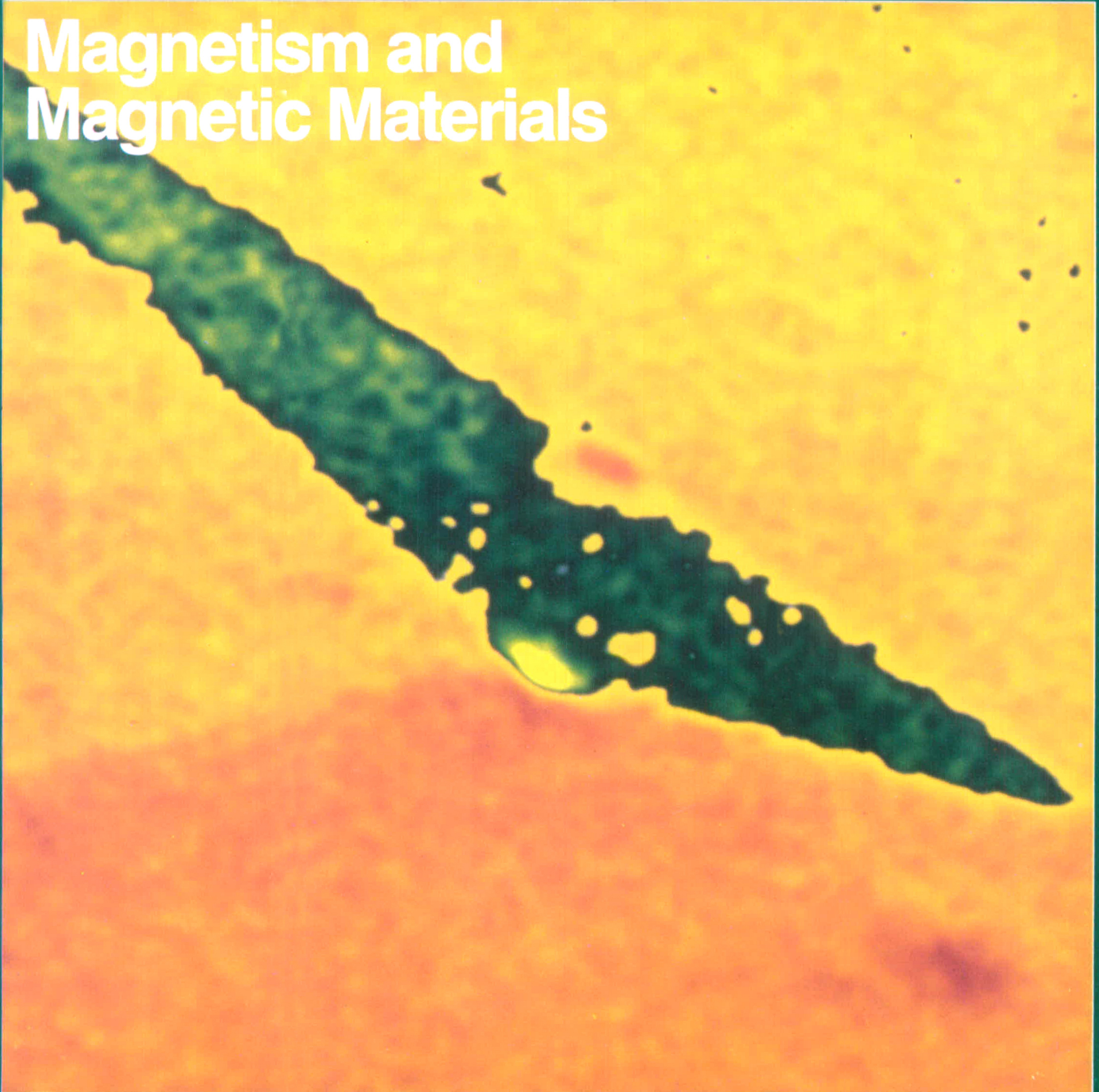

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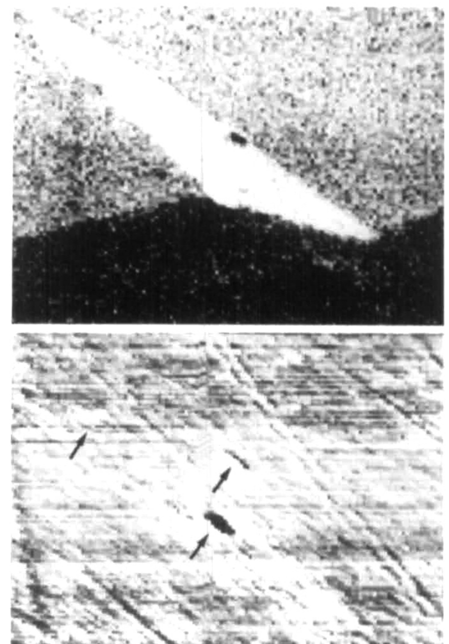

ON THE COVER: The cover shows a high resolution image of the specimen magnetization (with false color to emphasize different magnetic domains) obtained by SEMPA, Scanning Electron Microscopy with Polarization Analysis. The same secondary electrons that are measured to obtain the conventional surface topographic image yield information on the magnetic microstructure when the secondary electron spin polarization is measured. Defects observable in the topographic image (bottom photo) pin the domain walls of the dagger-shaped domain (top photo) as discussed in the article on p. 19 in this issue by researchers at the National Bureau of Standards.

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The Society's interdisciplinary approach to the exchange of technical information is qualitatively different from that provided by single-disciplinary professional societies because it promotes technical exchange across the various fields of science affecting materials development. MRS sponsors two major international annual meetings encompassing approximately 30 topical symposia, as well as numerous single-topic scientific meetings each year. It recognizes professional and technical excellence, conducts short courses, and fosters technical exchange in various local geographical regions through Section activities and Student Chapters on university campuses.

MRS is an Affiliated Society of the American Institute of Physics and participates in the international arena of materials research through associations with professional organizations such as European MRS.

MRS publishes symposia proceedings, the *MRS BULLETIN*, *Journal of Materials Research*, and other volumes on current scientific developments.

For further information on the Society's activities, contact MRS Headquarters, 9800 McKnight Road, Suite 327, Pittsburgh, Pennsylvania 15237; telephone (412) 367-3003; facsimile (412) 367-4373.

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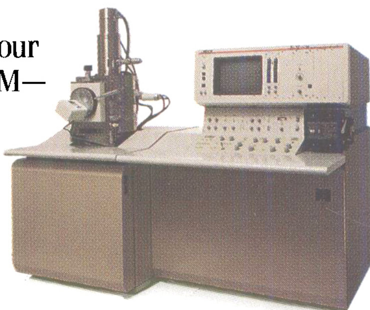

When you put a specimen into our high performance, imaging SEM—the JSM-820—you are going to get bright, clear, sharp images with an absolute minimum of operator effort.

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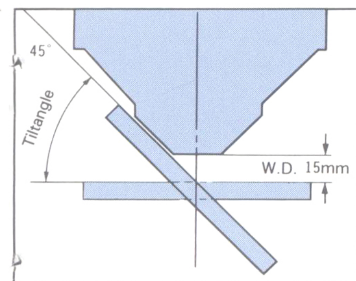

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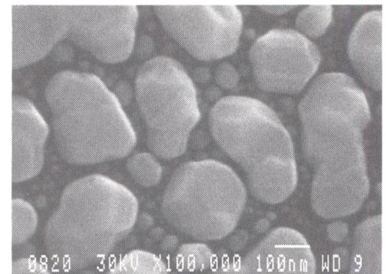

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